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## Contents

v Conference Committee

## **OPTICAL TESTING I** 13134 02 A dual-detection chromatic confocal probe employing a mode-locked femtosecond laser (Invited Paper) [13134-1] 13134 03 Aspherical surface measurement: a cost-effective and fast AI solution [13134-2] **OPTICAL TESTING II** 13134 04 Evaluating approximate and rigorous scattering models in virtual coherence scanning interferometry for improved surface topography measurement (Invited Paper) [13134-4] Absolute distance measurement using individual frequency modes of the electro-optic 13134 05 comb based on multiwavelength interferometry [13134-5] Study on phase measurement uncertainty according to the number of phase shifting steps 13134 06 in a multiwavelength interferometer directly using optical comb modes [13134-6] **OPTICAL TESTING III** 13134 07 Refractive optics metrology using on-axis deflectometry system [13134-8] Comprehensive analysis of surfaces featuring functional characteristics by angular-13134 08 resolved scattering light measurement [13134-10] **TELESCOPE SYSTEM I** Temporal variability in magnetically actuated deformable mirror surface figure measured 13134 09 via interferometry [13134-12] **TELESCOPE SYSTEM II** Focus diverse phase retrieval test results on broadband continuous wavefront sensing in 13134 0A space telescope applications [13134-16] 13134 OB A hybrid wavefront sensor: combining Shack-Hartmann and pyramid wavefront sensors to enable high dynamic range and sensitivity [13134-18]

	TELESCOPE SYSTEM III
13134 OC	Integration of off-axis freeform mirrors KASI deep rolling imaging fast telescope generation 1 (Invited Paper) [13134-19]
13134 0D	UVOIR to far-IR mirror technology development: year 2 status [13134-21]
	TELESCOPE SYSTEM IV
13134 OE	Optical alignment of the Roman space telescope's coronagraph instrument (Invited Paper) [13134-23]
13134 OF	Alignment of three mirror anastigmat telescopes using a multilayered stochastic parallel gradient descent algorithm [13134-22]
13134 0G	Big actuated three mirror anastigmat network [13134-25]
	OPTICAL MANUFACTURING I
13134 OH	Precision glass molding: towards a cost-efficient production of glass lenses using a multicavity approach [13134-28]
13134 OI	Measurement of mid-spatial frequencies of diamond turned optics by using dual-mode snapshot interferometry [13134-29]
13134 OJ	High speed laser-assisted diamond turning of tungsten carbide molds: an alternative to ultra-precision grinding $[13134\text{-}30]$
	OPTICAL MANUFACTURING II
13134 OK	Key aspects of sub-nanometer deterministic ion beam figuring for synchrotron hard x-ray mirror fabrication (Invited Paper) [13134-31]
	POSTER SESSION
13134 OL	A study on mechanical processing characteristics of Si grating [13134-37]
13134 OM	Design and test of small mirror supports for harsh environments [13134-40]
	DIGITAL POSTER SESSION
13134 ON	3D inspection of wire bonding using oblique-illumination optical sectioning microscopy [13134-42]